



PATENT APPLICATION

IN THE U.S. PATENT AND TRADEMARK OFFICE

November 3, 2003

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TC 1700

Applicant(s): Toshiaki MOTONAGA, et al

For: HALFTONE PHASE SHIFTING PHOTOMASK AND BLANKS FOR
HALFTONE PHASE SHIFTING PHOTOMASK THEREFOR AND A METHOD
FOR FORMING PATTERN BY USING THE HALFTONE PHASE
SHIFTING PHOTOMASK

Serial No.: 09/825 578

Group: 1756

Confirmation No.: 9940

Filed: April 3, 2001

Examiner: S. Rosasco

International Application No.: N/A

International Filing Date: N/A

Atty. Docket No.: OPS C-529

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Sir:

In response to the Office Action dated June 3, 2003,
please amend the above-identified application as follows:

(Please see following pages.)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service with
sufficient postage as first class mail in an envelope
addressed to: Commissioner for Patents, P.O. Box 1450,
Alexandria, VA 22313-1450, on November 3, 2003.


Mark L. Maki